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PATENT
03345-P0042A WWW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants	Johannes Kaeppler, et al.
Serial No. 10/685,233	Filing Date: October 14, 2003
Title of Application:	Method For Depositing Especially Crystalline Layers From The Gas Phase Onto Especially Crystalline Substrates
Confirmation No. 4633	Art Unit: 1762
Examiner	

Commissioner for Patents
Post Office Box 1450
Alexandria, VA 22313-1450

Supplemental Information Disclosure Statement by Applicants

As a means of complying with the duty of disclosure set forth in 37 CFR §1.56, Applicants list the following references (a copy of listed patent is enclosed).

U.S. Patent Documents				
Exam. Initials	Class/ Subclass.	Document No.	Date	Name
	118/730	5,702532	12/1997	Wen et al.

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May 12, 2004

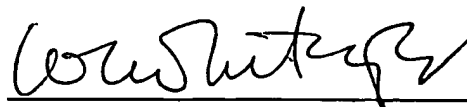
Gregory D. Venuto

Page 2 v62
Serial No. 10/685,233
Information Disclosure Statement

The listed patent pertain in a general way to the subject matter of the application,
but are not necessarily considered to be analogous prior art.

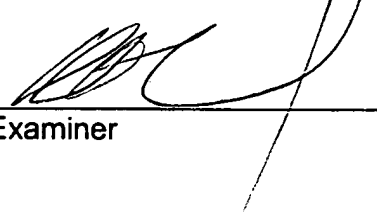
Respectfully submitted,

May 12, 2004



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Date Considered


Examiner



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U.S. Patent Documents				
Exam. Initials	Class/ Subclass.	Document No.	Date	Name
	118/48	3,690,290	9/1972	Jarvela et al.
	117/84	5,660,626	8/1997	Sato et al.
	438/478	6,080,642	6/2000	Van Geelen et al.
	117/90	6,086,673	7/2000	Molnar

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March 4, 2004

Gregory D. Veruto



Foreign Patent Documents

Exam. Initials	Document No.	Date	Country
<i>[Signature]</i>	0 687 749 A1	12/1995	EP

Other Documents

Exam. Initials	Description (Author, Title, Date, Pages, etc)
<i>[Signature]</i>	P.M. Frijlink, A New Versatile, Large Movpe Recator, Journal of Crytal Growth, Nov./Dec. 1998, nos 1-4. pages 207-215.
<i>[Signature]</i>	H. Jurgensen, Large-scale MOVPE production systems, Microelectronic Engineering, May 18, 1992, Nos. 1/2, pages 119-148.
<i>[Signature]</i>	O.Scheon, M. Schwambara, B. Schineller, D. Schmitz, M. Heuken and H. Jurgensen; High quality III-nitride material grown in mass production MOCVD systems, Journal of Crystal Growth, 1998. pages 297-303.

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